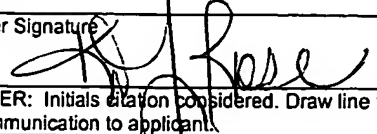


Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 07977-024004	Application No.
Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR §1.98(b))		Applicant Isamu Kobori et al.	
		Filing Date	Group Art Unit

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
RR	AA	5,413,958	05/95	Imahashi, et al.			
	AB	5,529,630	06/96	Imahashi, et al.			
	AC	5,595,923	01/97	Zhang, et al.			
	AD	5,712,191	1/27/98	Nakajima, et al.			
	AE	5,731,613	3/24/98	Yamazaki, et al.			
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	AN						

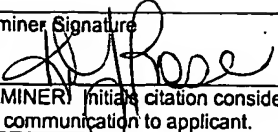
Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AO	05, 009,089 A	01/1993	Japan				
	AP	01-222432	09/05/89	Japan			ABS	
	AQ	06-260643	09/16/94	Japan			ABS	
	AR	2-150017	06/08/90	Japan			ABS	
	AS	2-224255	09/06/90	Japan			ABS	
	AT	6-84793	03/25/94	Japan			ABS	
	AU	6-124962	05/06/94	Japan			ABS	
	AV							

Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Signature 	Date Considered 2/8/05
EXAMINER: Initials drawn considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

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		Filing Date	Group Art Unit

Examiner Initial	Desig. ID	Document
	AW	Y. Fukushima, et al., "A Poly-Si TFT Process for High Speed and Low Voltage CMOS Circuits", Extended Abstracts of the 1993 International Conference on Solid State Devices and Materials, Makuhari, pp. 993-995, 1993.
	AX	

Examiner Signature 	Date Considered 2/8/05
EXAMINER: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	